

Notice of References Cited	Application/Control No. 10/790,759		Applicant(s)/Patent Under Reexamination MARUYAMA, EIJI	
	Examiner Jack Smith		Art Unit 1709	Page 1 of 1

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*	B	US-7,030,413	04-2006	Nakamura et al.	257/79
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	L	US-			
	M	US-			

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NON-PATENT DOCUMENTS

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	U	D.G. Neerincx and T.J. Vink, "Depth profiling of thin ITO films by grazing incidence X-ray diffraction", Thin Solid Films 278 (1996) 12 - 17.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.